



**International  
Standard**

**ISO 11505**

**Surface chemical analysis —  
General procedures for quantitative  
compositional depth profiling by  
glow discharge optical emission  
spectrometry**

*Analyse chimique des surfaces — Modes opératoires généraux  
pour le profilage en profondeur compositionnel quantitatif par  
spectrométrie d'émission optique à décharge lumineuse*

**Second edition  
2025-06**

ISO 11505:2025

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Published in Switzerland

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## Foreword

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The procedures used to develop this document and those intended for its further maintenance are described in the ISO/IEC Directives, Part 1. In particular, the different approval criteria needed for the different types of ISO document should be noted. This document was drafted in accordance with the editorial rules of the ISO/IEC Directives, Part 2 (see [www.iso.org/directives](http://www.iso.org/directives)).

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This document was prepared by Technical Committee ISO/TC 201, *Surface chemical analysis*, Subcommittee SC 8, *Glow discharge spectroscopy*.

This second edition cancels and replaces the first edition (ISO 11505:2012), which has been technically revised.

The main changes are as follows:

- the listed types of array detectors have been updated;
- advances in measurement techniques and apparatus have expanded the applicable sample sizes, and modifications have been made to optimize the optics, vacuum and detection systems;
- the text “setting of the high voltage for the detectors” is replaced with “setting of the parameters for detector sensitivity” throughout the documents;
- the instructions to optimize the crater shape has been changed from mandatory to optional.

Any feedback or questions on this document should be directed to the user's national standards body. A complete listing of these bodies can be found at [www.iso.org/members.html](http://www.iso.org/members.html).

